

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	IS&R	L1	2337	(257/234,252-254,414-420).CCLS.	USPAT	2008/03/28 15:10
2	IS&R	L2	2353	(257/234,252-254,414-420).CCLS.	US-PGPUB; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:11
3	BRS	L3	30410	MEMS micro near2 electro near2 mechanical near2 system	USPAT	2008/03/28 15:13
4	IS&R	L4	1708	(438/48,50,52,53).CCLS.	USPAT	2008/03/28 15:14
5	BRS	L5	422	3 and 4	USPAT	2008/03/28 15:14
6	BRS	L6	442742	MEMS micro near2 electro near2 mechanical near2 system	US-PGPUB; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:14
7	IS&R	L7	1315	(438/48,50,52,53).CCLS.	US-PGPUB; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:15
8	BRS	L8	385	6 and 7	US-PGPUB; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:15
9	BRS	L9	10	MEM and (fixing adj part) and (driving adj part) and (electrode) and (contact contacts) and substrate	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:26

	Type	L #	Hits	Search Text	DBs	Time Stamp
10	BRS	L10	2	((MEMS micro near2 electro near2 mechanical near2 system) and (fix\$5 adj part) and (driv\$5 adj part) and (electrode) and (planar\$8)).clm.	US-PGPUB	2008/03/28 15:43
11	BRS	L11	3	((MEMS micro near2 electro near2 mechanical near2 system) and (fix\$5 adj part) and (driv\$5 adj part) and (electrode) and (planar\$8)).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:44
12	BRS	L12	8	((MEMS micro near2 electro near2 mechanical near2 system) and ((fixed fixing) adj part) and ((drive driving) adj part) and (electrode) and (planar\$8))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	2008/03/28 15:46